# MICRO-BUBBLE GENERATING DEVICE AND SILICON WAFER CLEANING APPARATUS


## ABSTRACT

To provide a micro-bubble generating device and a silicon wafer cleaning apparatus which can supply a micro-bubble with a small bubble size which is high in a cleaning effect to the outside, and which can miniaturize a device and can enhance a flexibility of disposition thereof.

A micro-bubble generating device 1 is provided with a micro-bubble generating mechanism 10 and a leading conduit 20 which leads the micro-bubble outside. The leading conduit 20 is provided with a widening section 21 and a tube part 22, and the widening section 21 and the tube part 22 are connected and communicated to each other in the leading conduit 20. The widening section 21 has a hollow cylinder shape which makes an axis Z as a central axis, and has base surfaces 23, 24 and a peripheral surface 25 of a cylindrical shape, and communicates to a nozzle 11 of the micro-bubble-generating mechanism 10 via one base surface 23 of the widening section 21, and communicates to the tube part 22 via the other base surface 24. An area of a cross section which is orthogonal to a flow passage axis Z of the micro-bubble of the widening section 21 is larger than the area of the cross section which is orthogonal to the flow passage axis Z of the tube part 22.

[Selected Drawing]

FIG. 1